

# Ellipsometry Parameters

Most of the researchers using ellipsometry techniques describe their results in terms of the parameters  $\Psi$  and  $\Delta$ . These parameters are directly related to settings of the analyser and polariser in a null ellipsometer, but are not intrinsically fundamental. They are related to the fundamental quantity  $r$ , a complex quantity with real and imaginary parts  $r_r$  and  $r_i$  by the relation

$$r = r_p / r_s = r_r + ir_i = \tan \Psi e^{i\Delta} = \rho e^{i\Delta} .$$

$\Delta = \delta_p - \delta_s$  is the phase difference between the p and s waves, while  $\tan \Psi$  is the amplitude of  $r$ .

Thus

$$\rho = \tan \Psi, \quad r_r = \rho \cos \Delta, \quad r_i = \rho \sin \Delta .$$

We believe that ellipsometer researchers would simplify their life considerably if they used  $r_r$  and  $r_i$  as the significant parameters when describing and reporting their data.

Consider, as an example, the locus of  $r$  when a layer of varying thickness is placed on a substrate. This is a commonly occurring situation. The locus in the complex plane of  $r$  is close to an ellipse, but is of a quite different shape when the locus of  $\Psi$  versus  $\Delta$ , or alternatively of  $\tan \Psi$  versus  $\Delta$ , are shown.

Two examples are given below. In the first we model a protein layer on water, in the second an oxide layer on silicon. Figure 1 shows how  $r$  depends on layer thickness for each of the two examples. For both we have chosen an angle of incidence equal to the Brewster angle where  $r_r = 0$  for zero layer thickness. Water is a transparent substrate so that  $r_i$  also equals zero at the Brewster angle. Silicon has a small imaginary component to its dielectric constant in the infrared, so again  $r_i$  starts from very near zero. Figures 2 and 3 show the plots of  $r_i$  vs  $r_r$  and  $\Psi$  vs  $\Delta$ , respectively. In neither case does  $\Psi$  come really close to  $\pi$ , so that  $\Psi$  and  $\tan \Psi$  have a similar behaviour and we only show  $\Psi$  versus  $\Delta$

Note that  $\Delta$  changes rapidly from  $\pi$  to  $-\pi$  near the origin, giving the semblance that this is a special point on the locus. In fact it is just part of a smooth curve having no inherent singularity associated with it.

The properties of the layer locus will be discussed further in another Technical Note, but in passing it should also be noted that the locus of  $r$  in the complex plane becomes exactly a circle when the layer is self-supporting (the incident medium and the substrate have the same dielectric constant).

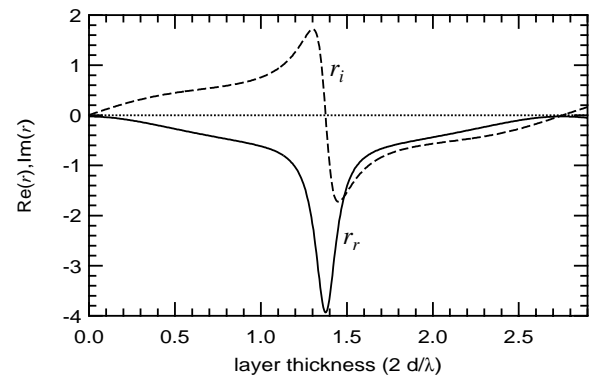
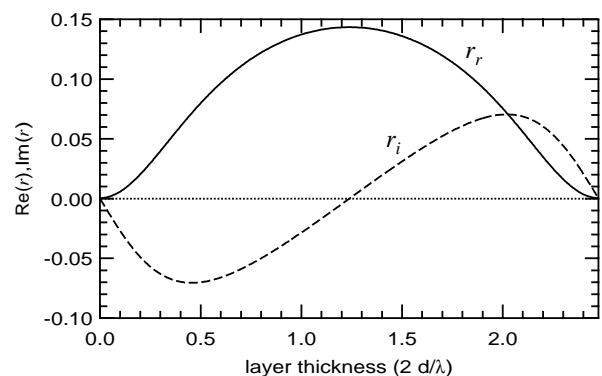
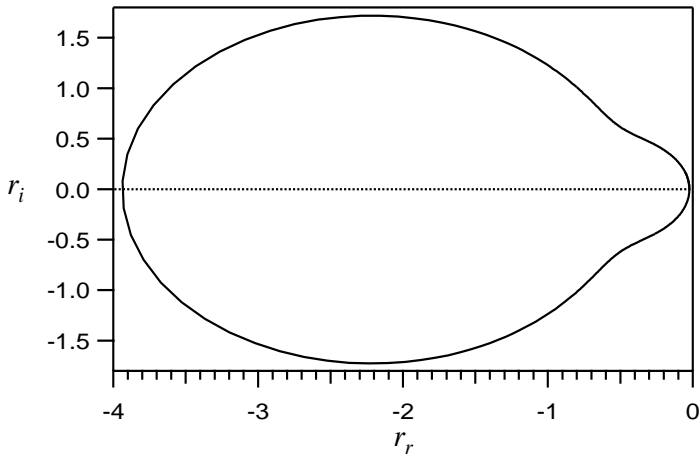
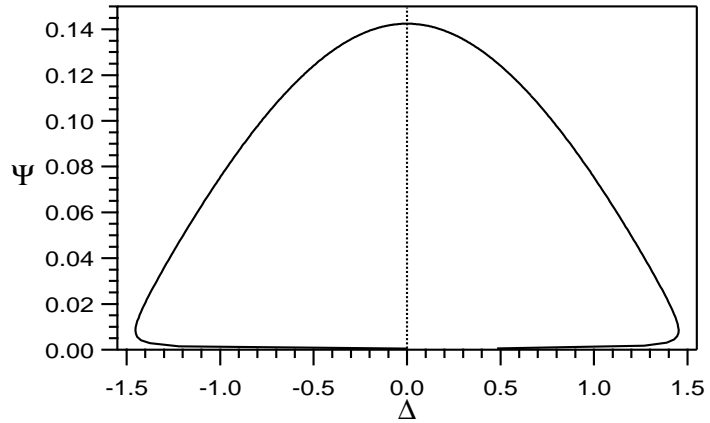
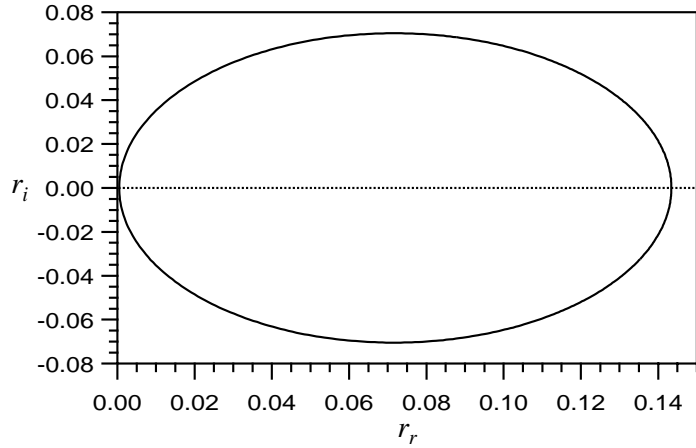


Figure 1: These two figures show  $r_r$  and  $r_i$  for a protein layer on water (above), and an oxide layer on silicon (below). In both cases  $\epsilon = 2.25$ , for water  $\epsilon_2 = 1.78$ , for silicon  $\epsilon_2 = 19.1 + i 0.5$ , and the angles of incidence are 53.13 and 77.65 degrees. The thickness is shown in the dimensionless units  $2\pi d / \lambda$ .

**Protein on Water**

Figure 2: The locus of  $r_i$  versus  $r_r$  (above) and  $\Psi$  versus  $\Delta$  (below), for the case of protein on water. Note how the smooth curve around  $r_i = 0$  is distorted to become a rapid variation in  $\Delta$ .



**Oxide on Silicon**

Figure 3: The locus of  $r_i$  versus  $r_r$  (above) and of  $\Psi$  versus  $\Delta$  (below), for an oxide layer on silicon.

